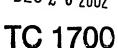


FORM PTO-1449 INFORMATION DISCLOSURE CITATION IN AN APPLICATION PURSUANT TO				Docket Number:					
				Applicant: Ye et al.					
37 CFR §1.97 & 1.98					Filing Date:				
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Sheet 1 of 1

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					Filing Date:	Group) :		
					February 19, 2002	1725			
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	Μ.	Alexandra	EIV						

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation not in conformance and not considered. Include copy of this form with next communication to the applicant.